

1. Record Nr.	UNISA996279842603316
Titolo	2016 21st International Conference on Ion Implantation Technology (IIT) // Institute of Electrical and Electronics Engineers
Pubbl/distr/stampa	Piscataway, NJ : , : IEEE, , 2016 ©2016
ISBN	1-5090-2024-1
Descrizione fisica	1 online resource (87 pages)
Disciplina	621.38152
Soggetti	Ion implantation
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Nota di bibliografia	Includes bibliographical references and index.
Sommario/riassunto	Annotation The conference will cover topics on ion implantation technology and thermal processing for semiconductor devices and materials including junction, contact, material modification, process modeling and metrology methods.